



Industrial Consultancy & Sponsored Research (IC&SR)

Apparatus for varying resonant frequency in a multi-frequency radio frequency (RF) Micro-Electro-Mechanical System (MEMS) switch **IITM Technology Available for Licensing**

Problem Statement

Indian Institute of Technology Madras

□ The problem statement discussed in the present invention is how to vary resonant frequency in a radio frequency (RF) MEMS capacitive switch.

□ Hence, subject invention addresses the issue.

Technology Category/Market

Technology:; Apparatus for varying resonant frequency in a multi-frequency RF Micro-Electro-Mechanical System (MEMS) switch **Industry/Application:** RF MEMS Switch.

ESDM; Market: The global RF MEMS market is projected to reach at a CAGR of 13.08% during the period (2024-32).

Technology

- □ Present patent describes an **apparatus** for varying resonant frequency in a multifrequency radio frequency (RF) Micro-Electro-Mechanical System (MEMS) capacitive switch. (Refer Fig.1 & Fig. 2)
- □ The apparatus includes a multi-frequency RF MEMS capacitive switch, a plurality of floating metals spaced uniformly in the multi frequency RF MEMS capacitive switch, a lateral thermal actuator, a push-pull beam with a contact arm and a plane tip or a Tshaped tip and a buckling actuator.
- □ The buckling actuator, the push-pull beam and the lateral thermal actuator are in the same horizontal plane in the initial state (ON -state of the switch).
- \Box Further, a first (1st) direct current (DC) voltage is applied to the lateral thermal actuator and a second (2nd) DC voltage is applied to the **buckling actuator**.

□ The buckling actuator buckles upward from a first (1^{st}) position to a 2nd position when the second (2nd) DC voltage is applied to the buckling actuator.

- □ The **push-pull beam** is pushed laterally by the lateral thermal actuator towards the plurality of floating metals when the 1st DC voltage is applied to the lateral thermal actuator.
- □ The **voltages** can be applied to the buckling actuator and the lateral thermal actuator at the same time or at different times.
- □ The **former** case, the distance of separation between the buckling actuator and the push-pull beam and the 1st & 2nd voltages to be applied on them are optimized so as to assure that the buckling actuator has moved upward displacing itself from the path of the push-pull beam.
- The latter case, the distance of separation and the voltages are not timedependent, unlike the former case.
- □ Moreover, each of the floating metal is segmented.

TRL (Technology Readiness Level)

TRL-4, Technology validated in Lab;

Intellectual Property

IITM IDF Ref. 1339; Patent No. 363823

Research Lab

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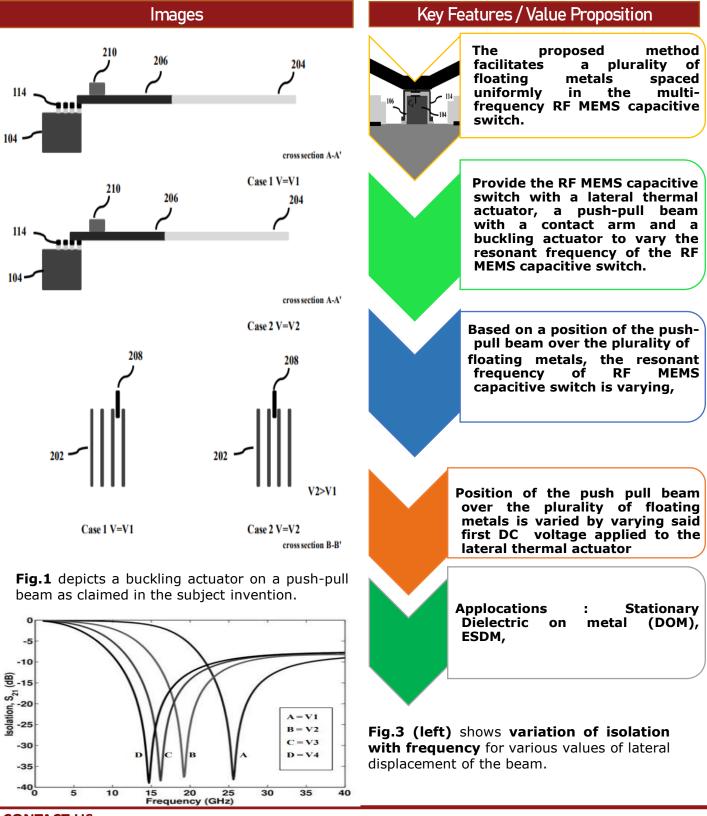
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